

Slater & Matsil, L.L.P.**RECEIVED****CENTRAL FAX CENTER**

Suite 1000

17950 Preston Road

Dallas, Texas 75252-5793

Phone: 972-732-1001 Facsimile: 972-732-9218

JUN 23 2005**FACSIMILE COVER SHEET**

To: Examiner Thanh Y. Tran	Total Pages Sent: 5
Technology Center 2800	(including cover sheet)
Facsimile Number: 703-872-9306	Transmission Date: June 23, 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Haupt Docket No.: INTECH 3.0-104 (2003 P 51718 US)

Serial No: 10/766,053 Art Unit: 2822

Date Filed: January 28, 2004


Title: Method for N+ Doping of Amorphous Silicon and Polysilicon Electrodes in Deep Trenches

CERTIFICATION OF FACSIMILE TRANSMISSION

I hereby certify that the following papers are being transmitted by facsimile to the U.S. Patent and Trademark Office at 703-872-9306 on the date shown above:

- Certification of Facsimile Transmission (1 page)
- Petition for Extension of Time Under 37 CFR 1.136(a) (1 original and 1 copy)
- Election (2 pages)

Respectfully submitted,


Anne Marie James
Legal Assistant**RECEIVED**
OIPE/IAP**JUN 27 2005****Confirmation Respectfully Requested**

This facsimile is intended only for the use of the address named and contains legally privileged and/or confidential information. If you are not the intended recipient of this telecopy, you are hereby notified that any dissemination, distribution, copying or use of this communication is strictly prohibited. Applicable privileges are not waived by virtue of the document having been transmitted by Facsimile. Any misdirected facsimiles should be returned to the sender by mail at the address indicated on this cover sheet.